

Abstract

Substrate for Supporting an Object, and Method for Producing Said Substrate

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10 The invention relates to a substrate (10) for an object (12), preferably a substrate for a semiconductor element such as a wafer, with a mount for the object, and gas outlet openings that extend below the mount, along the object held in the mount. In order that a desired gas is able to exit, in proper proportions and finely dispersed, via the gas outlet openings, it is proposed that the substrate (10) is comprised at least in segments of a material made of stabilized fibers (18, 20) having a porosity level that forms the gas outlet openings.

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Fig. 1

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